# **1** Photovoltaic high-performance broadband photodetector based

2

# on MoS<sub>2</sub>/Si nanowire array heterojunction

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# 13 Abstract

- 14 Photovoltaic MoS<sub>2</sub>/Si nanowire array (SiNWA) heterojunction photodetectors (PDs)
- 15 are constructed and investigated, which exhibit excellent photoresponse properties to
- 16 light illumination at wavelengths from the deep ultraviolet to the near-infrared.
- 17 Further photoresponse analysis reveals that a high responsivity of 53.5 A/W and a
- specific detectivity of  $2.8 \times 10^{13}$  Jones, as well as fast response speeds of 2.9/7.3 µs at
- 19 50 kHz are achieved in a MoS<sub>2</sub>/SiNWA heterojunction device. The high performances
- could be attributed to the high-quality heterojunction between  $MoS_2$  and the SiNWA.
- 21 Such high performances of MoS<sub>2</sub>/SiNWA PDs are much better than those of
- 22 previously reported MoS<sub>2</sub>-based PDs, suggesting that MoS<sub>2</sub>/SiNWA heterojunction
- 23 devices have great potential in optoelectronic applications.
- 24 Keywords: molybdenum disulfide, heterojunction, Si nanowire arrays, photodetectors,
- 25 self-powered
- 26

# 1 **1. Introduction**

The discovery of graphene has inspired great interest in exploring the promising 2 potential of two-dimensional (2D) layered semiconductor nanostructures for their 3 enormous applications in electronic and optoelectronic devices based on their specific 4 geometries and unique physical properties [1-3]. With atomically thin, stacked with 5 van der Waals force and free of surface chemical dangling bonds, 2D layered 6 semiconductor nanostructures provide an open platform for exploring novel physical 7 phenomena and mechanisms [4, 5]. However, the widespread applications of the 8 9 pristine graphene in electronics and optoelectronics were limited by its zero band-gap. Transition metal dichalcogenides (TMDs), especially the those with atomic thickness, 10 have been emerged as a new class of nanomaterials for fundamental studies and 11 12 promising applications due to their distinct properties [6, 7]. Molybdenum disulfide (MoS<sub>2</sub>) is one of the most widely studied layered material due to its inherent and 13 layer-dependent band-gaps [8-11]. Crystals of MoS<sub>2</sub> are composed of vertically 14 15 stacked, weakly interacting layers through van der Waals interactions. When the layers of MoS<sub>2</sub> decreased to monolayer, it will transform to a direct-gap with 1.9 eV 16 from the indirect-gap with 1.2 eV. This unique property grants the great advantages 17 for high-performance devices with high on/off ratio and low power consumption 18 19 [12-14]. Besides, few-layer MoS<sub>2</sub> can response light signals from ultraviolet (UV) to near infrared (NIR) because of the narrower band-gap, which is beneficial to design a 20 variety of photodetectors (PDs) [15]. All these features revealled that MoS<sub>2</sub> has 21 important potential applications in electronic and optoelectronic devices. 22

Compared with traditional bulk materials, 2D materials based PDs have several 1 natural advantages, such as wide detection range, free of dangling bonds at the 2 3 surfaces and strongly interact with incident light [16]. In spite of these advantages, 2D materials based PDs have their drawbacks, such as low absorptivity of incident light, 4 large dark current and small light on/off ratio, and low detectivity. To overcome these 5 drawbacks, diverse device structures and various enhancing methods have been 6 developed. Constructing heterojunction is a promising way to enhanced the device 7 performancs, which can improve the separation efficiency of photoexcited 8 9 electron-hole pairs [17]. Hence, an increasing interest has been attracted by heterojunction devices of 2D materials [18, 19]. From previous reports, the 10 photoconductor based PDs usually have high responsivities, with slow response 11 12 speeds, whereas, the junction-based PDs always hold the advantage in fast response speeds [17]. For example, Andras Kis et al. reported a single-layer MoS<sub>2</sub> 13 photoconductor with a high responsivity of 880 A/W, but slow response speeds of 4/9 14 15 s (rise/fall time) [20]. Jie et al. reporteded a MoS<sub>2</sub>/Si heterojunction PD with fast response speeds of 3/40 µs and a low responsivity of 0.3 A/W [21]. And the similar 16 results were also reported by us and Jiang et al [22, 23]. These heterojunction devices 17 are mainly based on planar Si with poor light harvesting capability, which may lead to 18 the low responsivity. Achieving a high responsivity and a fast response speed 19 simultaneously in a single MoS<sub>2</sub>-based PD is an urgently desired for practical 20 21 optoelectronic applications in the future.

22

Silicon (Si), one of the most important optoelectronic materials in the

semiconductor industry, is widely used in commercial PDs, PV devices and 1 semiconductor chips due to their high performance as well as the mature large-scale 2 3 production and integration technologies [24-26]. Si nanostructures, and in particular, Si nanowire arrays (SiNWA) have received increasing attention in recent years due to 4 their unique properties in terms of enhanced light absorption and excellent electron 5 transport characteritic. In addition, enhanced device performances have been 6 demonstrated in PV devices and PDs by using SiNWAs as light harvesting candidates 7 [27-30]. Inspired by these progresses, it is anticipated that combing MoS<sub>2</sub> with 8 9 SiNWAs may lead to heterojunction PDs with both high responsivities and fast response speeds. 10

Herein, the photovoltaic MoS<sub>2</sub>/SiNWA heterojunction PD was constructed, and 11 its optoelectronic properties were systematically investigated. This PD has exhibited 12 excellent rectifying characteristics and photoresponse properties with pronounced 13 photovoltaic effect. Therefore, it can serve as a self-powered PD, which can operate at 14 15 voltage bias of 0 V. The photoresponse properties of the MoS<sub>2</sub>/SiNWA heterojunction PD were studied, displaying excellent repeatability and stability with high current 16 on/off ratio, high responsivity, specific detectivity, as well as fast response speeds. 17 The method presented in this work is an efficient way to improve the performances of 18 19 2D materials based PDs.

20 **2. Experimental Details** 

#### 21 2.1 Synthesis and characterization of layered MoS<sub>2</sub> thin films

22 The few-layer  $MoS_2$  thin films used in this work were fabrictated *via* a thermal

decomposition method, which has been described in our previous work [23, 31]. The 1 crystal structure of the as-fabricated samples were analyzed by an X-ray diffraction 2 3 (XRD, X' Pert Pro, Panalytical, Netherlands), glancing incidence angle XRD (GIAXRD, SmartLab, Rigaku, Japan) and high-resolution transmission electron 4 microscopy (HRTEM, JEM-2010, JEOL, Japan). X-ray photoelectron spectroscopy 5 (XPS, ESCALAB 250, Thermo Fisher Scientific, USA) was performed to examine 6 the component. Raman spectrum was obtained with a Raman spectroscopy 7 (LabRAM HR Evolution, Horiba, Japan). The thickness was detected by an atomic 8 9 force microscope (AFM, Dimension Icon, Bruker, USA). Absorption spectra of SiNWAs, and bulk Si were acquired with a UV-VIS-NIR spectrophotometer (UH4150, 10 Hitachi, Japan). 11

#### 12 2.2 Construction of the MoS<sub>2</sub>/SiNWA heterojunction devices

The vertical ordered SiNWAs were fabricated by etching *n*-type Si wafer with an Ag-assisted chemical etching method [32]. Then, the MoS<sub>2</sub> film was transferred onto the top of SiNWA with a polymethyl methacrylate (PMMA)-assisted process, as demonstrated in Fig. 2c. An electrode of 50 nm Au on the MoS<sub>2</sub> film was defined by a thermal evaporation with a shadow mask. Meanwhile, another electrode of Cu sheet was connected to the cross section of Si substrate *via* high-purity silver conducting paint. A schematic of a MoS<sub>2</sub>/SiNWA heterojunction PD was shown in Fig. 3a.

#### 20 *2.3 Device performance characterization*

The device performances of PD were investigated with a semiconductorcharacterization system (Keithley 4200-SCS, Tektronix, USA), combining with a

1 spectrometer (Omni-λ300, Zolix, China), an oscilloscope (DPO2012B, Tektronix,

# **3 3. Results and Discussions**

Fig. 1a shows the XRD and GIAXRD patterns of the as-prepared MoS<sub>2</sub> films on 4 quartz substrates. A strong (002) peak was shown at  $2\theta = 14.3^{\circ}$ . In addition, a (105) 5 peak at  $2\theta = 50.6^{\circ}$  and a (106) peak at  $2\theta = 56.0^{\circ}$  were also observed in GIAXRD 6 patterns. From the HRTEM image as shown in Fig. 1b, the MoS<sub>2</sub> has a hexagonal 7 lattice structure with the lattice spacing of 0.27 nm assigned to the (100) and (010) 8 9 planes. From Raman spectroscopy as shown in Fig. 1c, the layer number of MoS<sub>2</sub> can be identified by the energy difference between the  $E_{2g}$  and  $A_{1g}$  Raman modes ( $\Delta$ ) [33]. 10 A  $\Delta$  of 24.0 cm<sup>-1</sup> indicates that the MoS<sub>2</sub> film is few-layer, which was further 11 12 confirmed by AFM (~3.1 nm), as shown in Fig. 1d. According to XPS analysis (Fig. 1e and 1f), Mo binding energies of 229.3 and 232.5 eV corresponding to Mo 3d5/2 13 and Mo 3d3/2, respectively, and S binding energies of 162.2 and 163.3 eV 14 15 corresponding to 2p3/2 and S 2p1/2 orbitals are observed.

To construct MoS<sub>2</sub>/SiNWA heterojunction devices, the SiNWAs were prepared as shown in Fig. 2a. SEM images show that the length of Si nanowires was about 3 μm. Fig. 2b depicts the absorption spectra of the SiNWA and Si wafer. From the curves, the light absorption of the SiNWAs is much enhanced compared to the Si wafer, at the entire UV-VIR-NIR wavelength region, which is beneficial to improve the responsivity of PDs. After obtaining the high-quality few-layer MoS<sub>2</sub> films and SiNWAs, the MoS<sub>2</sub>/SiNWA heterojunction devices were fabricated as shown in Fig. 1 2c.

A schematic of the MoS<sub>2</sub>/SiNWA heterojunction device was shown in Fig. 3a. Fig. 3b depicts the current-voltage (*I-V*) curves of the MoS<sub>2</sub>/SiNWA and MoS<sub>2</sub>/bulk Si heterojunction devices in the dark and under light illuminations of 650 nm with an intensity of 38.6 mW cm<sup>-2</sup>. From which, the excellent rectification characteristic of the MoS<sub>2</sub>/SiNWA heterojunciton with a rectification ratio up to  $10^2$  within ±5 V can be obtained in the dark. For an ideal diode, the I-V characteristic can be described by the following equation:

9 
$$I = I_0 (e^{qV_{DS}/nk_BT} - 1)$$
 (1)

10 Therefore, the ideality factor n can be expressed as:

11 
$$n = \frac{q}{K_B T} \frac{dV}{d\ln I}$$
(2)

12 where  $I_0$ ,  $K_B$  and T represent the reverse bias leakage current, the Boltzmann constant and the temperature in Kelvin, respectively. By fitting the rectification curve, a small 13 ideality factor n of 1.05 can be obtained in the low-bias zone, which is consistent with 14 the theoretical value (n = 1) [34]. Under light irradiation, the current became strong in 15 both forward and reverse directions, leading to a high current on/off ratio (Ion/Ioff) over 16  $10^3$  at -5 V. It is worth noting that the dark current of the MoS<sub>2</sub>/SiNWA device is 17 much lower than the value of the MoS<sub>2</sub>/bulk Si device, whereas the photocurrent of 18 the MoS<sub>2</sub>/SiNWA device is much larger than that of the MoS<sub>2</sub>/bulk Si device. It is 19 believed that the contact area of MoS<sub>2</sub> and Si, and the higher absorptivity of incident 20 21 light of SiNWA are responsible for these differences.

22 Moreover, pronounced photovoltaic behaviors were observed under light

1	illumination of 650 nm, and an open-circuit photovoltage (Voc) of 0.29 V and short
2	circuit current ( $I_{SC}$ ) of 18.6 µA were obtained at a light intensity of 38.6 mW cm <sup>-2</sup>
3	(Inset of Fig. 3b). Therefore, this MoS <sub>2</sub> /SiNWA heterojunction device can serve as a
4	self-powered PD. The photoresponse of MoS <sub>2</sub> /SiNWA PD under different bias
5	voltages were investigated, as shown in Fig. 3c. The stable and repeatable
6	photoresponse with different $I_{on}/I_{off}$ ratios can be observed when the light (650 nm,
7	38.6 mW cm <sup>-2</sup> ) was turned on and off. The $I_{on}/I_{off}$ ratios can be deduced to $1.1 \times 10^5$ ,
8	3.6×10 <sup>2</sup> , 7.5×10 <sup>2</sup> and 3.0×10 <sup>3</sup> under bias voltages of 0 V, -1 V, -2 V and -5 V,
9	respectively, which are much larger than $3.15 \times 10^2$ of MoS <sub>2</sub> /bulk Si heterojunction
10	devices, and values reported previously [21, 23]. Fig. 3d shows the response spectrum
11	of the MoS <sub>2</sub> /SiNWA PD, from which, an obvious photoresponse over a wide
12	wavelength range from UV to NIR (300-1200 nm) can be observed. Moreover, the
13	striking response properties to deep UV of 250 nm and NIR of 1200 nm at voltage
14	bias of 0 V were shown in Fig. 3e and f, indicating that such $MoS_2/SiNWA$
15	heterojunction PD has great potential application in broadband photodetection.

Light intensity is a key factor that determines the photocurrent in PDs. The light intensity-dependent photoresponse of the MoS<sub>2</sub>/SiNWA PD were further studied as shown in Fig. 4a. It depicts that the I-V curves of the MoS<sub>2</sub>/SiNWA PD under varied light intensities from dark to 38.6 mW cm<sup>-2</sup>. The *I*<sub>SC</sub> is highly dependent on the light intensity and increase with increasing light intensity. The *I*<sub>SC</sub> *versus* the light intensity was plotted in Fig. 4b, which can be described as:

22

# $I=AP^{\alpha}$

(3)

where A is a constant. The exponent  $\alpha$ , which determines the response of the 1 photocurrent to light intensity, can be determined to be 0.8. This fractional power 2 3 dependence is believed to be related to the carrier trap states between the Fermi level and the conduction band edge [35]. The photoresponses of MoS<sub>2</sub>/SiNWA PD at zero 4 bias under different light intensities were also investigated, as shown in Fig. 4c. From 5 the curves, stable and repeatable photoresponses with high  $I_{on}/I_{off}$  ratios of  $3.2 \times 10^2$ , 6  $2.9 \times 10^3$ ,  $2.8 \times 10^4$  and  $1.1 \times 10^5$  could be obtained under light intensities of 0.031, 0.46, 7 4.5 and 32 mW cm<sup>-2</sup>, respectively. As two important parameters of PD, responsivity 8 (R) and specific detectivity (D\*) can be calculated according to the following 9 relations: 10

11 
$$R = \frac{I_P - I_d}{P_{opt} \cdot S}$$
(4)

12 
$$D^* = \frac{\sqrt{AR}}{\sqrt{2eI_d}}$$
(5)

where Ip, Id, Popt, S and A are the photocurrent, dark current, the incident light 13 14 intensity, the area of light illumination and device area, respectively. Hence, the light intensity-dependent responsivity and specific detectivity are shown in Fig. 4d. Both R 15 and D\* increased with the decreasing light intensity and can be estimated to be 53.5 16 A/W and 2.8×10<sup>13</sup> Jones (1 Jones =1 cm Hz<sup>1/2</sup> W<sup>-1</sup>) under a light intensity of 6.3  $\mu$ W 17 cm<sup>-2</sup>, which are much larger than the values obtained for the MoS<sub>2</sub>/bulk Si device.[23] 18 Another figure of merit for PD is the linear dynamic range (LDR), which is defined 19 20 by the following equation: [16]

$$LDR = 20\log \frac{I_P^*}{I_d} \tag{6}$$

where I<sub>P</sub>\* represents the photocurrent measured at a light intensity of 1 mW cm<sup>-2</sup>. A
LDR of 72.8 dB at zero bias can be obtained, which is better than 42 dB of WS<sub>2</sub>/n-Si,
and 66 dB of the commercialized InGaAs photodiodes [36-38].

The response speed is another key parameter for PDs, representing their ability 4 to monitor quick varying optical signals. In this work, the photoresponse properties of 5 the MoS<sub>2</sub>/SiNWA PD were further evaluated by modulating the frequency of the 6 incident light with a waveform generator. And the photocurrent was monitored by an 7 oscilloscope with time, as shown in Fig. 5. Fig. 5a-c show the repetitive switching of 8 9 the PD between low and high conduction states when the laser diode was turned on and off regularly at frequencies of 500 Hz, 3000 Hz and 10 kHz, respectively. From 10 the figure, the MoS<sub>2</sub>/SiNW PD could operate with excellent stability and repeatability 11 12 over a wide frequency range up to 150 kHz under a light intensity of 38.6 mW cm<sup>-2</sup>. Moreover, the relative balance  $[(I_{\text{max}}-I_{\text{min}})/I_{\text{max}}]$  of the photocurrent can remain at 77% 13 under a high frequency of 10 kHz, implying that this MoS<sub>2</sub>/SiNW PD is capable of 14 15 monitoring ultrafast optical signals. The 3 dB bandwidth ( $f_{3dB}$ ) of 13 kHz can be obtained from Fig. 5d, which is much large than the values of some reported PDs [39, 16 40]. In the time domain, the response speed of PDs is usually defined by the rise time 17  $(\tau_r)$  and the fall time  $(\tau_f)$ . From further analysis, a small  $\tau_r$  of 22.8 µs and  $\tau_f$  of 61.5 µs 18 19 were obtained at 4 kHz and 2.9/7.3 µs at 50 kHz, which are superior to or close to previous results [22, 41]. 20

Moreover, light intensity has been found to greatly influence the response speed
[42]. Hence, the response speed of a MoS<sub>2</sub>/SiNWA PD was investigated under varied

1	light intensities at a frequency of 4 kHz, as shown in Fig. 6. Rise times of 54.2, 27.7,
2	23.5 and 22.8 $\mu s,$ and fall times of 69.9, 68.6, 67.4 and 61.5 $\mu s$ were observed under
3	light intensities of 2.5, 16.8, 24.5 and 38.6 mW cm <sup>-2</sup> , respectively. It is worth noting
4	that the rise/fall time decreased with the increase in the incident light intensity. The
5	reduction of the time constants with increasing light intensity is in good agreement
6	with Rose's model [43]. To investigate the repeatability of this device, device
7	performance of five MoS <sub>2</sub> /SiNWA PDs, which were fabricated by the same process
8	and technology, were summarized in Table 1, demonstrating that these devices
9	showed similar device performances, proving that our devices have good
10	repeatability. Table 2 summarized the device performances of the MoS <sub>2</sub> /SiNWA PD
11	and some reported PDs. It is important to note that when Si substrate was replaced by
12	SiNWAs, the response speed maintained almost the same value, but the responsivity
13	and specific detectivity were much enhanced.
14	The internal resistance (R) and capacitance (C) of MoS <sub>2</sub> /Si heterojunction device
15	were investigated by electrical impedance spectroscopy (EIS). The simplified
16	equivalent circuit including the internal R and C are proposed to evaluate the interface
17	quality, as illustrated in Fig. 8a. The Nyquist plots of the MoS <sub>2</sub> /Si heterojunction was
18	investigated in the dark with an applied voltage of 0.06 V. The resistance $R_S$ , $R_{pn}$ and
19	$R_{Cu/Si}$ are estimated to be 2.4×10 <sup>3</sup> $\Omega$ , 1.9×10 <sup>6</sup> $\Omega$ and 1.4×10 <sup>4</sup> $\Omega$ , respectively.
20	Additionally, the capacitance $C_{pn}$ is obtained to $6 \times 10^{-9}$ F. The small Rs is beneficial to
21	transfer carrier, leading to larger photocurrent. And the high $R_{pn}$ can effectively
22	suppress the charge recombination, which will improve the device performance.

1	The fast response speed of MoS <sub>2</sub> /SiNWA PD is believed to be related to the
2	high-quality heterojunction between the MoS <sub>2</sub> and the SiNWA. The electron affinities
3	of $MoS_2$ and Si are ~4.3 eV and ~4.05 eV, and their band-gap values are known to be
4	~1.3 eV (MoS <sub>2</sub> ) and ~1.12 eV (Si) [12, 22, 44, 45], respectively. Such electronic
5	structures will decide the conduction and valence band offsets between the two
6	semiconductors being ~0.25 and ~0.33 eV, as shown in Fig. 7. When $MoS_2$ contacts
7	with Si, a typical n-n junction is formed [46]. Due to the ~250 meV for the conduction
8	band edge, $MoS_2$ is more negative than Si, and electrons would diffuse into $MoS_2$
9	from Si, while holes would diffuse into Si from MoS2. As a result, a built-in electric
10	field would be formed at the $MoS_2/Si$ interface. When the device was exposed to light
11	with engeries larger than the band-gap of the semiconductors, absorption of the
12	incident light would result in the generation of excitons on both the MoS <sub>2</sub> and Si sides.
13	Once the excitons diffuse into the interface of the junction, they are separated in
14	opposite directions by the built-in electric field at the interface. The electrons would
15	inject into MoS <sub>2</sub> , while the holes would drift to Si, leading to the fast response speed
16	and giving rise to the photocurrent in the external circuit. The built-in electric field
17	would reduce electron-hole recombination and prevent the transport of electrons from
18	the $MoS_2$ into Si, leading to a low reverse dark current and thus improving the
19	detectivity. Moreover, the built-in potential at the interface would allow device
20	operate at zero bias voltage, realizing the self-powered property.
21	4. Conclusions

22 In summary, large-scale few-layer MoS<sub>2</sub> thin films were synthesized via a thermal

decomposition method, and SiNWAs were obtained by Ag-assisted chemical etching 1 method. MoS<sub>2</sub>/SiNWA heterojunction devices were fabricated and investigated, 2 3 which exhibited pronounced photoresponse and photovoltaic properties. Further photoresponse analysis revealled that such MoS<sub>2</sub>/SiNWA PDs can work under zero 4 bias with high photosensitivities and fast response speeds. It is most important that a 5 high responsivity of 53.5 A/W, a specific detectivity of 2.8×10<sup>13</sup> Jones and a fast 6 response speed of 2.9/7.3 µs were achieved in a single device. The approach 7 demonstrated here could be extended to the study of other 2D materials-based 8 9 heterojunctions for high-performance PDs and may offer new possibilities toward practical optoelectronic applications. 10

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#### 1 Figures



**Fig. 1.** (a) XRD and GIAXRD patterns of MoS<sub>2</sub> thin film. (b) HRTEM and corresponding SAED pattern of MoS<sub>2</sub> thin film. (c) Raman spectrum, and (d) height profiles of a MoS<sub>2</sub> thin film. The XPS spectra show the binding energies of (e) Mo and (f) S of the MoS<sub>2</sub> thin film.

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2 Fig. 2. (a) SEM images of the SiNWA, inset shows the cross-section image. (b)

Absorption spectra of a SiNWA and bulk Si substrate. (c) Schematic diagram of a
 MoS<sub>2</sub>/SiNWA heterojunction device fabrication.



2 Fig. 3. (a) Schematic illustration of a MoS<sub>2</sub>/SiNWA heterojunction device. (b) I-V curves of MoS<sub>2</sub>/Si and MoS<sub>2</sub>/SiNWA heterojunction devices in the dark and under 3 4 light illumination (650 nm). Inset shows the photovoltaic effect of the MoS<sub>2</sub>/SiNWA 5 heterojunction device. (c) Photoresponse of the MoS<sub>2</sub>/SiNWA heterojunction under different bias voltages. (d) The sensitivities of the MoS<sub>2</sub>/SiNWA and MoS<sub>2</sub>/Si PDs as 6 7 a function of wavelength. Photoresponse of the MoS<sub>2</sub>/SiNWA heterojunction under incident light of (e) 250 nm (1.2  $\mu$ W/cm<sup>2</sup>) and (f) 1200 nm (100  $\mu$ W/cm<sup>2</sup>) at voltage 8 bias of 0 V. 9





**Fig. 5.** Photoresponse characteristics of the MoS<sub>2</sub>/SiNWA heterojunction to pulsed light irradiation at frequencies of (a) 500 Hz, (b) 3000 Hz and (c) 10 kHz at a voltage of 0 V. (d) The relative balance [( $I_{max}$ - $I_{min}$ )/ $I_{max}$ ] vs switching frequency, inset shows the schematic illustration of the measurement configuration for photoresponse detection. Rising and falling edges for estimating rise time ( $\tau_r$ ) and the fall time ( $\tau_f$ ) at (e) 4 kHz and (f) 50 kHz.



Fig. 6. (a) Rising and (b) falling edges of I-V curves at different light intensities (650 nm).





2 Fig.7. (a) The equivalent circuit model for the Nyquist plots. (b) Experimental

3 impedance spectrum (Nyquist plots) of MoS<sub>2</sub>/SiNWA heterojunction device.





2 Fig. 8. Energy band diagrams of the MoS<sub>2</sub>/SiNWA heterojunction (a) at equilibrium

- 3 (in the dark condition), and (b) under light illumination.
- 4
- 5

Devices	I <sub>on</sub> /I <sub>off</sub>	Responsivity [A/W]	Detectivity [Jones]	Rise/fall time [µs]
1	1.1×10 <sup>5</sup>	<mark>53.5</mark>	2.8×10 <sup>13</sup>	2.9/7.3 (10 kHz) 22.8/61.5 (4 kHz)
<mark>2</mark>	<mark>0.98×10<sup>5</sup></mark>	<mark>49.2</mark>	1.95×10 <sup>13</sup>	<mark>31.3/67.5</mark>
<mark>3</mark>	1.22×10 <sup>5</sup>	<mark>48.6</mark>	2.25×10 <sup>13</sup>	25.6/72.1
<mark>4</mark>	1.54×10 <sup>5</sup>	<mark>51.8</mark>	2.54×10 <sup>13</sup>	<mark>23.6/67.6</mark>
<mark>5</mark>	1.63×10 <sup>5</sup>	<mark>55.6</mark>	3.19×10 <sup>13</sup>	<mark>26.5/76.7</mark>

# **Table 1.** Summary of the device performances of five MoS<sub>2</sub>/SiNWA PDs

**Table 2.** Summary of the device performances of the MoS<sub>2</sub>/SiNWA PD and some reported PDs.

Daviaas type	I <sub>on</sub> /I <sub>off</sub>	Responsivity	Detectivity	Rise/Fall time	Ref.
Devices type		[A/W]	[Jones]	[µs]	
MoS <sub>2</sub> /SiNWA	1.1×10 <sup>5</sup>	53.5	2.8×10 <sup>13</sup>	2.9/7.3	This work
MoS <sub>2</sub> /Si	59.9	11.9	$2.1  imes 10^{10}$	30.5/71.6	[22]
MoS <sub>2</sub> Schottky PD	~10 <sup>2</sup>	0.57	$\sim 10^{10}$	70/110	[41]
MoS <sub>2</sub> /Gaphene	<1	0.032	/	>10 <sup>6</sup> /10 <sup>6</sup>	[47]
MoS <sub>2</sub> /Black Phosphorus	/	22.3	$3.1\times10^{11}$	15/70	[48]
WS2/Si	~10	5.7	/	670/998	[49]
Graphene/Si	~104	0.73	~10 <sup>12</sup>	320/750	[50]